



Thin-Film Devices for Healthcare and Environmental Sensing

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Message from the Guest Editor

Transducers based on thin-film technologies promise to be extremely reliable and low in cost, but the control of the properties at their interfaces is essential for operating them in a selective and sensitive manner. Furthermore, the development of thin-film-based sensors for long-term monitoring is an exciting but challenging perspective that can find many applications in the healthcare domain, where the environment may be harsh and difficult to access. Thin films can be fabricated from a wide range of materials, whose properties can be tuned according to the type of transduction mechanism. For example, sensors based on the combination of thin-film technologies with electrochemical and electrical transduction have demonstrated tremendous improvement in terms of limits of detection and stability. This Special Issue aims to seek recent advances in novel thin-film strategies for sensing purposes, thin-film electrochemical sensors, thin-film electrical sensors (i.e., field-effect transistor sensors), and recent developments in sensing technologies for long-term monitoring.

We look forward to receiving your submissions.





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Message from the Editor-in-Chief

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